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501.30414V22
ac

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: KATO, et al.

Serial No.: 09/766,596

Filed: January 23, 2001

For: VACUUM PROCESSING APPARATUS AND OPERATING
METHOD THEREFOR

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FURTHER SUPPLEMENTAL PRELIMINARY AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

January 14, 2002

Sir:

Prior to examination of the above-identified application, and
supplementing the Preliminary Amendment filed January 23, 2001, and
Supplemental Preliminary Amendment filed May 29, 2001, please further amend
the above-identified application as follows:

IN THE CLAIMS

Please rewrite the claims presently in the application as follows:

27. (Amended) A conveyor system for processing substrates in plural
vacuum processing chambers, the conveyor system including:
- a loader;